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WHAT IS CLAIMED IS:

- A method for manufacturing a semiconductor device comprising steps of:
- 5 fixing semiconductor chips onto a substrate; covering the semiconductor chips fixed onto the substrate with a common resin layer;

gluing an adhesive sheet onto the resin layer;
cutting the substrate and the resin layer in a state
that the adhesive sheet is glued to the resin layer; and
measuring the semiconductor devices in a state that the
adhesive sheet is glued to the resin layer.

 A method for manufacturing a semiconductor device according to claim 1,

wherein the substrate and the resin layer is cut from the reverse surface of the substrate in a state that the adhesive sheet is glued to the resin layer.

 A method for manufacturing a semiconductor device according to claim 1,

wherein the substrate and the resin layer which are cut are integrally supported by the adhesive sheet.

4. A method for manufacturing a semiconductor device

according to claim 1,

wherein the substrate and the resin layer is cut by performing dicing in a state that the adhesive sheet is glued to the resin layer.

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A method for manufacturing a semiconductor device according to claim 1,

wherein external electrodes are provided on the reverse surface of the substrate and electrically connected to the semiconductor chips.

6. A method for manufacturing a semiconductor device according to claim 1, further comprising a step of:

flattening the surface of the resin layer after covering the semiconductor chips with the resin layer.

7. A method for manufacturing a semiconductor device according to claim 1,

wherein the circumferential edge of the adhesive sheet 20 is fixed to a metal frame.

 A method for manufacturing a semiconductor device according to claim 7,

wherein a plurality of the substrates are glued to the $\mbox{25}$ adhesive sheet.

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 A method for manufacturing a semiconductor device according to claim 1, further comprising steps of:

fixing semiconductor chips onto a substrate;

covering the semiconductor chips fixed onto the substrate with a common resin layer;

gluing an adhesive sheet onto the resin layer;
cutting the substrate and the resin layer in a state
that the adhesive sheet is glued to the resin layer;

measuring the semiconductor devices in a state that the adhesive sheet is glued to the resin layer;

peeling the resin layer from the adhesive sheet after performing the measurement of the semiconductor devices; and directly storing the semiconductor device peeled from the adhesive sheet in a carrier tape.

 A method for manufacturing a semiconductor device according to claim 9,

wherein the substrate and the resin layer is cut from the reverse surface of the substrate in a state that the adhesive sheet is glued to the resin layer.

- A method for manufacturing a semiconductor device according to claim 9,
- 25 wherein the substrate and the resin layer which are cut

are integrally supported by the adhesive sheet.

- A method for manufacturing a semiconductor device according to claim 9.
- 5 wherein the substrate and the resin layer is cut by performing dicing in a state that the adhesive sheet is glued to the resin layer.
 - A method for manufacturing a semiconductor device according to claim 9,

wherein external electrodes are provided on the reverse surface of the substrate and electrically connected to the semiconductor chips.

14. A method for manufacturing a semiconductor device according to claim 9, further comprising a step of:

flattening the surface of the resin layer after covering the semiconductor chips with the resin layer.

20 15. A method for manufacturing a semiconductor device according to claim 9,

wherein the circumferential edge of the adhesive sheet is fixed to a metal frame.

25 16. A method for manufacturing a semiconductor device

according to claim 10,

wherein a plurality of the substrates are glued to the adhesive sheet. $\ensuremath{\mathsf{S}}$